

MATERIAL	Toxic Rating		RF/DC	Power %	Bias (V)	O2 flow (sccm)	Ar flow (sccm)	Temperature (°C)	Pressure (mT)	Expected rate (nm/min)	Measured rate (nm/min)	Method
	1 to 5	Gun										
Ag	1	3	DC	2			20	28	2.5	2.5	2.4	RBS
Al		5	DC	20			20		2.5		10	
Al	1	6	RF	50			20	18	4	3.6	5	SEM/Filmt ek
Au	1	3	DC	5			20	18	2.5	5.3	5.47	RBS
Bi		3	DC	3			20	18	3		5.2	
Co	1	2	DC	20	418		20	18	4		5	Dektak
Cr NC	1		RF	30	265		20	18	4		4.5	Dektak
Cr	1	6	RF	30			20	18	4	3.24	2.58	RBS
Cu	1	3	DC	10			20	18	4		5	Optical Prof
Er	2	5 or 6										
Fe		2	DC	5	300		20	18	4		1.6666667	Dektek
Ge	1	6	RF	20			20	18	4	3.5	3.25 - 3.38	RBS
			RF	50			10	10	4		2.35	ELLIP
			RF	50			15	5	4		2.66	ELLIP
Hf												
La												
Mg	1	3 or 6										
Mo		3	DC	10	330		20	18	4		3.66	Stylus
Nb	3	3	DC	30	400		20	18	4		6.4	Dektek
NiO		2	DC	20	390	2	18	18	4	-	13	Stylus
Ni	1	2	DC	20			20	18	4		9	
Pd	3	6	RF	30	105		20	18	4		8.03	Stylus
Pt	1	3	DC	20			20	18	4	14.4	11.74	RBS
Sn		6	DC	5	350		20	18	4		9.7777778	Dektek
Sn	2	6	DC	1	278		20	18	4		1.6	Stylus
Sb		5	DC	10	450		20	18	4		17.5	
Sb		5	DC	3			20	18	4		6	
Sb		5	DC	1			20	18	4		1	
Si	6		RF	50			20		4		3.28	

R = 0.0646*RF

Si			DC	20			20	18	4		2.27	
Si	1	6	RF	40			20	18	4	1.8	2.34	STYLUS
Ta	1	6	RF	50	100	0	20	18	4		7	STYLUS
Te	3	6	DC	3			20	18	3		14.6	
Ti	1	5	RF	50			20	18	4	3	3	RBS
W	1	6	DC	20	415		20	18	3		6	Dektek
Graphite	1	3	DC	35	608		20	18	2.5		1.11	
zn			dc	5			20	18			15	

$$R = 0.0606 * RF$$